

PATENT APPLICATION  
Docket No. 1383-002  
Client No. FP05033/US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): Kyung Woon KIM

Serial No. 10/538,388 Examiner: Tai, XiuYu

Filed: June 13, 2005 Group Art Unit: 1795

Confirmation No: 5784

For: PLASMA REACTOR AND ELECTRODE PLATE USED IN THE  
SAME

Date: May 4, 2009

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO RESTRICTION REQUIREMENT**

Responsive to the Restriction Requirement, dated March 3, 2009, please amend the application as follows:

**IN THE CLAIMS**

1-4. (Cancelled)

5. (Original) A plasma reactor comprising:

more than two electrode plates, each electrode plate including a dielectric member and an electrode protected from a discharge space by the dielectric member and having an electric-connecting coupling hole on one side and a non-electric-connecting coupling hole on the other side, the electric-connecting coupling hole having a shoulder on which the electrode is exposed, the electrode plates being stacked such that a gap is interposed between the adjacent electrode